## CLAIMS

- 1. A two-layer laminated film for forming bumps, comprising:
- 5 (I) a lower layer comprising a composition including a polymer (A) and an organic solvent (B); and
  - (II) an upper layer comprising a negative radiation-sensitive resin composition;

the polymer (A) including a structural unit represented 10 by Formula (1):

[Chem. 1]

$$\begin{array}{c} \begin{array}{c} R_4 \\ \hline \\ CH_2 - C \\ \hline \\ O = C \\ \hline \\ R_1 \\ \hline \\ R_2 \\ \hline \\ OH \\ \end{array}$$

wherein  $R_1$  is  $-(CH_2)_n$ - where n is an integer of 0 to 3, and  $R_2$ ,  $R_3$  and  $R_4$  are the same or different from one another and are each a hydrogen atom or an alkyl group of 1 to 4 carbon atoms.

- 2. The two-layer laminated film for forming bumps according to claim 1, wherein the negative radiation-sensitive resin composition for the upper layer (II) includes a polymer having a carboxyl group and/or a phenolic hydroxyl group (C), a crosslinking agent (D), a radiation-activated radical polymerization initiator (E), and an organic solvent (F).
- 3. The two-layer laminated film for forming bumps according to claim 2, wherein the polymer (C) has a glass transition temperature (Tg) of not less than 40°C.
- 4. A transfer film comprising the laminated film claimed in claim 1 and a support film on which the laminated film is provided.

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- 5. A process for forming bumps on electrode pads on a wiring board, comprising at least:
- (a) a step of providing the two-layer laminated film claimed in claim 1 on a substrate and forming a pattern of apertures at positions corresponding to electrode pads;
- (b) a step of introducing a low-melting metal in the apertures;
- (c) a step of reflowing the low-melting metal by heating to form bumps; and

- (d) a step of peeling and removing the two-layer laminated film from the substrate.
- 6. A process for forming bumps on electrode pads on5 a wiring board, comprising at least:
  - (a) a step of providing the two-layer laminated film claimed in claim 1 on a substrate and forming a pattern of apertures at positions corresponding to electrode pads;
- (b) a step of introducing a low-melting metal in the 10 apertures;
  - (d') a step of peeling and removing the two-layer laminated film from the substrate; and
  - (c') a step of reflowing the low-melting metal by heating to form bumps.